



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Francisco ARIAS et al.

Examiner:

Mathieu D. VARGOT

Serial No.: 10/727,124

Group Art Unit:

1732

Filing Date: December 3, 2003

Confirmation No:

4751

Title: METHOD OF MANUFACTURING MICRONEEDLE STRUCTURES USING SOFT LITHOGRAPHY AND PHOTOLITHOGRAPHY

**AMENDMENT UNDER 37 CFR § 1.111**

**AND REQUEST FOR EXTENSION OF TIME**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is in response to the Office Action mailed from the PTO on March 13, 2007. A one-month extension of time is requested. The fee for the extension accompanies this response. Please amend the application as indicated herein.

The *Listing of the Claims* begins on page 2 of this document. Claims 2, 10, and 14 are amended.

*Remarks* begin on page 6 of this document.

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